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## INFORMATION DISCLOSURE STATEMENT

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**Applicant Kenji KASAHARA t al.**

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**U.S. PATENT DOCUMENTS**

[illegible]

## FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
GE	11-219133	8/10/99	Japan	1	1	Abstract	
				1	1		
				1	1		
				1	1		
				1	1		

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

GSE	K. Shimizu et al., "High-Mobility Poly-Si Thin-Film Transistors Fabricated by a Novel Excimer Laser Crystallization Method", IEEE Transactions on Electron Devices, Vol. 40, No. 1, pp. 112-117, 1993. ●
GSE	F. Secco d'Aragona, "Dislocation Etch for (100) Planes in Silicon", J. Electrochem. Soc., Vol. 119, No. 7, pp. 948-951, 1972. ●

Examiner Heather Evans

Date Considered November 14, 2008

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.